

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Antonio L. P. Rotondaro

Docket No:

TI-31133

Serial No:

10/001,483

Conf. No:

1903

Examiner:

Michelle Estrada

Art Unit:

2823

Filed:

11/01/2001

For:

METHOD TO IMPROVE THE UNIFORMITY AND REDUCE THE SURFACE ROUGHNESS

OF THE SILICON DIELECTRIC INTERFACE

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner For Patents P.O. Box 1450 Alexandria, VA 22313-1450

MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a) I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 5-9-03.

Dear Sir:

Responsive to the Office Action mailed February 10, 2003, in connection with the above identified application, Applicant respectfully submits the following remarks.